

Notice of References Cited	Application/Control No. 10/718,824	Applicant(s)/Patent Under Reexamination IVANOVIC ET AL.	
	Examiner Nithya Janakiraman	Art Unit 2123	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"IMD- Software for modeling the optical properties of multilayer films", David L. Windt, Bell Laboratories, Murray Hill, New Jersey. March 31, 1998.
	V	"Optical Analysis of Complex Multilayer Structures Using Multiple Data Types", Blaine Johs, et al. Optical Interference Coating, SPIE Vol. 2253, 1994.
	W	"Optical Lithography Simulation and Photoresist Optimization for Photomask Fabrication", Benjamin M. Rath sack et al. Department of Chemical Engineering, The University of Texas at Austin. May 1999.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.